

Notice of References Cited	Application/Control No. 10/625,772	Applicant(s)/Patent Under Reexamination UCHIYAMA ET AL.	
	Examiner Daniel I. Walsh	Art Unit 2876	Page 1 of 1

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*	B	US-2005/0110640	05-2005	Chung, Kevin Kwong-Tai	340/572.1
*	C	US-2004/0036623	02-2004	Chung, Kevin Kwong-Tai	340/825.49
*	D	US-2003/0052788	03-2003	Kwong-Tai Chung, Kevin	340/573.1
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	U	Position Monitoring with Hall Effect Sensors (http://www.sensorsmag.com/articles/0902/52/main.shtml) September 2002.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.